

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Hiroshi HAJI, et al. :
Serial No.: : Group Art Unit:
Filed: February 13, 2001 : Examiner:
For: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE



7/IDS
8/7/03
✓

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Respectfully submitted,

MCDERMOTT, WILL & EMERY


Michael E. Fogarty
Registration No. 36,139

600 13th Street, N.W.
Washington, DC 20005-3096
(202) 756-8000 MEF:klm
Date: February 13, 2001
Facsimile: (202) 756-8087